

AMENDMENTS TO THE CLAIMS

The following listing of claims replaces all prior versions of claims in the application.

1. (Currently Amended): A mounting apparatus for ~~fixing a semiconductor wafer to a ring frame~~ by sticking a dicing tape to ~~[[said]]~~ a ring frame having a ~~in a state that the~~ semiconductor wafer ~~[[is]]~~ disposed in an inside area of said ring frame ~~disposed on a table~~, comprising:

supporting means for supporting a strip material ~~attaching~~ including a film corresponding to the ~~for forming~~ dicing tape ~~tapes~~ stuck on ~~[[one]]~~ a surface of a base sheet;

pre-cutting ~~pre-cut~~ means for ~~forming a dicing tape by~~ forming a cut in said film of said ~~in accordance with the size of said ring frame to the~~ strip material fed from the supporting means in accordance with the size of the ring frame, thereby forming the dicing tape;

a peeling plate ~~peeling means~~ for peeling said dicing tape from said base sheet off the ~~dicing tape, said peeling plate being located more towards the~~ downstream of said pre-cutting ~~means in~~ the sheet feeding direction ~~than the pre-cut means;~~ and

a press roller positioned at a downstream end of said peeling plate in the sheet feeding ~~direction~~ pressing means for ~~fixing the semiconductor wafer to the ring frame by~~ pressing the dicing tape ~~the peeled dicing tape~~ onto the ring frame.

2. (Previously Presented): The mounting apparatus according to claim 1, wherein a tension control means is disposed between said supporting means and said pre-cut means, wherein

the tension control means comprises a dancer roller, which is movable vertically so as to allow the strip material to be fed out toward said pressing means while giving tension due to its

own weight to said strip material, and first and second sensors for detecting a raised position and a lowered position of the dancer roller respectively, and wherein,

when the first sensor detects said dancer roller at the raised position, said supporting means feeds out the strip material by a predetermined amount to lower the dancer roller, and when the second sensor detects the dancer roller at the lowered position, said supporting means stops feeding out the strip material therefrom.

3. (Withdrawn): A mounting method in which a ring frame is disposed on a table, a semiconductor wafer is disposed in an inside area of the ring frame, and a dicing tape is stuck onto said ring frame to fix the semiconductor wafer to the ring frame, comprising the steps of:

forming a cut in said film in accordance with the size of said ring frame in a process of feeding out a strip material attaching a film for forming dicing tapes stuck on one surface of a base sheet;

peeling off the dicing tape formed inside said cut from the base sheet; and

moving the dicing tape and said table relative to each other to stick said dicing tape onto the semiconductor wafer and the ring frame, thereby fixing the semiconductor wafer to the ring frame.

4. (Withdrawn): The mounting method according to claim 3, wherein a tension control means is disposed between said supporting means and a pre-cut means, wherein,

the tension control means comprises a dancer roller, which is movable vertically so as to allow said strip material to be fed out toward said sticking means while giving tension due to its own weight to said strip material, and first and second sensors for detecting a raised position and a lowered position of the dancer roller respectively, and wherein,

the following operations are repeated; i.e., when the first sensor detects said dancer roller at the raised position, said supporting means feeds out the strip material of a predetermined amount to lower the dancer roller, and when the second sensor detects the dancer roller at the lowered position, said supporting means stops feeding out the strip material therefrom.